

SOEI/0057 UNASSIGNED

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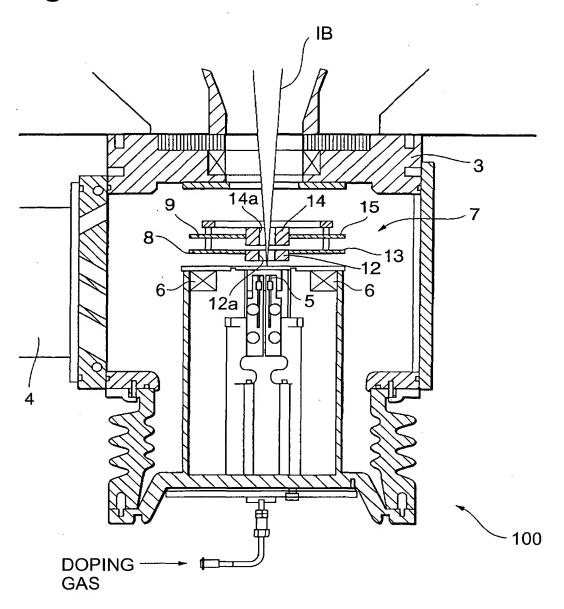
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HEREWITH
APPLIED MATERIALS, INC.
ION IMPLANTATION METHOD, SOI WAFER MANUFACTURING METHOD
AND ION IMPLANTATION SYSTEM
ITO, ET AL.

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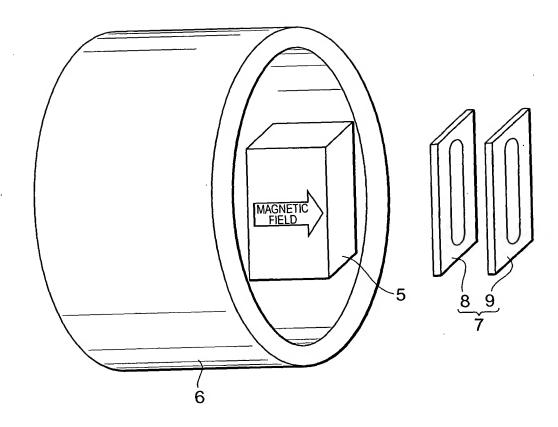
Fig.2



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Fig.3



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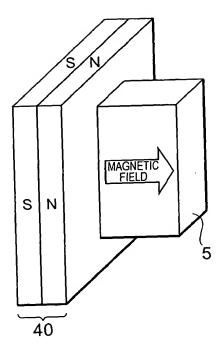
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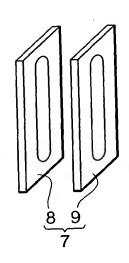
PAGE 3 Of 8

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PAGE 3 of 8

Fig.4





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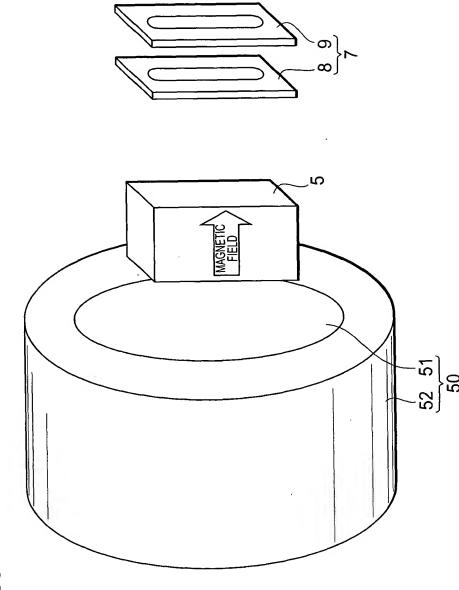
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PAGE 4of 8



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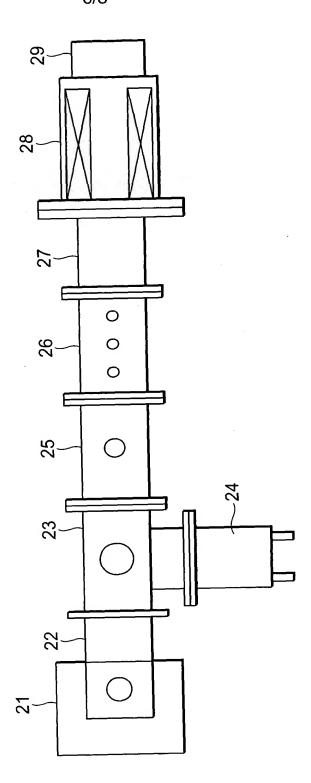
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PAGE 5 of 8

6/8



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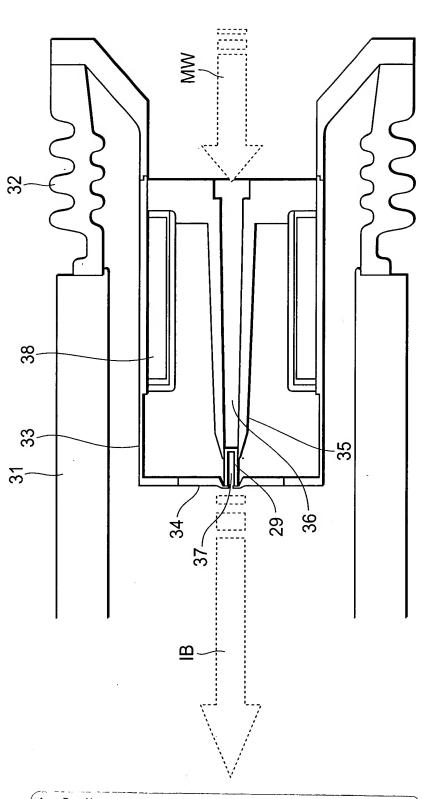
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PAGE 6.of 8

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7/8



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PAGE 7_of_8

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